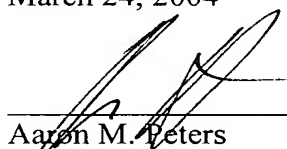




PATENT
30320/14617A

IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE

Applicant: Doros, Theodore G.)	I hereby certify that this paper is
Serial No.: 10/728,404)	being deposited with the United
Filed: December 5, 2003)	States Postal Service with
For: Methods and Apparatus for Off-Axis)	sufficient postage as first class
Lithographic Illumination)	mail in an envelope addressed to:
Attorney Docket No.: 30320/14617A)	Commissioner for Patents, P.O.
Group Art Unit: 2875)	Box 1450, Alexandria, Virginia
Examiner: Not Yet Assigned)	22313-1450 on this date:
)	March 24, 2004
)	
)	Aaron M. Peters
)	Registration No. 48,801
)	Attorney for Applicant

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Pursuant to 37 CFR 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached Form PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

Copies of the references on the Form PTO-1449 are not provided.

In accordance with 37 CFR 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR 1.56(a) exists. In accordance with 37 CFR 1.97(h), the filing of this Information Disclosure statement shall not be construed to be an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

TIME OF FILING

This information disclosure statement is being filed to the best of the undersigned's knowledge, before the mailing date of a first Office action on the merits. In accordance with 37 CFR §1.97(b), no certification or fee is required.

PRIOR AND RELATED APPLICATIONS

In accordance with 37 CFR §1.98(d), copies of the patents and publications listed on the enclosed PTO Form-1449 are not provided because the patents and publications were previously cited by the Patent Office in a prior application that Applicant relies upon for an earlier filing date under 35 U.S.C. §120. Documents listed on the attached Form PTO-1449 were cited by the examiner of the following patent application:

Applicant: Doros, Theodore G.
Serial No.: 10/334,882
Filing Date: December 31, 2002
Title: Methods and Apparatus for Off-Axis Lithographic Illumination
Status: Issued as U.S. Pat. No. 6,703,625

METHOD OF PAYMENT

It is submitted that the Information Disclosure Statement is in compliance with 37 CFR 1.98 and the Examiner is respectfully requested to consider the listed references.

The Director is hereby authorized to charge any deficiency in the fees filed, asserted to be filed or which should have been filed herewith (or with any paper hereafter filed in this application by this firm) to our Deposit Account No. 13-2855, under Order No. 30320/14617A. A duplicate copy of this paper is enclosed.

Dated: March 24, 2004

Respectfully submitted,

By 

Aaron M. Peters

Registration No.: 48,801

MARSHALL, GERSTEIN & BORUN LLP

233 S. Wacker Drive, Suite 6300

Sears Tower

Chicago, Illinois 60606-6357

(312) 474-6300

Attorney for Applicant



For PTO-1449 (Modified) INFORMATION DISCLOSURE STATEMENT	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. 30320/14617A	Serial No. 10/728,404
	Applicant Doros, Theodore G.		
	Filing Date December 5, 2003	Group 2875	

U.S. PATENT DOCUMENTS							
*Examiner Initials		Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate
		5361292	11-1-94	Sweatt	378	34	
		5638211	6-10-97	Shiraishi	359	559	
		6109756	8-29-00	Takahashi	359	857	
		6233041	5-15-01	Shiraishi	355	53	
		6452662	9-17-02	Mulkens et al.	355	67	4-6-99
		6525806	2-25-03	Smith	355	71	6-29-00

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
		Sewell, "The Development of Step and Scan," Semiconductor Fabtech, 9 th Edition, pp. 193-197
		Schellenberg et al., "Adoption of OPC and the Impact on Design and Layout," Session 7-4, Design Automation Conference, June 19, 2001
		Rieger et al., "Layout Design Methodologies for Sub-Wavelength Manufacturing," Website, 20 pages, (undated), found at: http://videos.dac.com/videos/38th/7/7_3/7_3_slides.pdf
		"Lithography Stepper Optics", Website, 10 pages, (undated), found at: http://www-inst.eecs.berkeley.edu/~ee290f/lithoslides.pdf
		Hsu et al., "Dipole Decomposition Mask-design for Full Chip Implementation at the 100nm Technology Node and Beyond," Optical Microlithography XV, Proceedings of SPIE, Vol. 4691, © 2002, pp. 476-490

Examiner	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	